

VERSION WITH MARKINGS TO SHOW CHANGES MADE

In the Claims

1. (Once amended) A semiconductor manufacturing apparatus for a photolithographic process including a coating process and a developing process, the apparatus comprising:
 - a first port where a substrate comes in and goes out;
 - a second port, having a constant distance from the first port, where the substrate comes in and goes out;
 - coating means[, coupling the first port to the second port, for carrying the substrate between the first port and the second port and] for performing the coating process; and
 - developing means[, coupling the first port to the second port, for carrying the substrate between the first port and the second port and] for performing the developing process, the developing means being stacked in parallel with [on] the coating means [in line.],
 - wherein the coating means includes:
 - a first conveyance path extending horizontally for coupling the first port to the second port;
 - a coating module arranged along one side of the first conveyance path extending horizontally; and
 - a first carrier, which moves between the first port and the second port via the first conveyance path, for carrying a substrate to the first port or the second port of the coating module.
2. (Once amended) The apparatus of Claim 1, [wherein the coating means includes:
 - a first path which couples the first port to the second port;
 - a coating module which is arranged along one side of the first path; and
 - a first carrier, which moves between the first port and the second port, for carrying a substrate to the first port or the second port or the coating module,]wherein the developing means includes:
 - a second conveyance path extending horizontally for coupling [which couples] the first port to the second port;

A

a developing module which is arranged along one side of the second conveyance path;
and

a second carrier, which moves between the first port and the second port via the second conveyance path, for carrying the substrate to the first port or the second port or the developing module.

5. (Once amended) The apparatus of Claim [2] 1, wherein the coating module includes:
a coater which is arranged at one side of the first conveyance path; and
a bake unit which is arranged at the other side of the first conveyance path and opposite to the coater[, and wherein the developing module includes:
a developer which is arranged at one side of the second path; and
a bake unit which is arranged at the other side of the second path and opposite to the developer].

Claim 8 is new.

Claim 9 is new.